FUSION IN SITU HEATING AND ELECTRICAL



STUDY MATERIALS WITH THERMAL AND ELECTRICAL CHARACTERIZATION

> Correlate your results with TEM & SEM imaging and analysis tools

PtCo Nanoparticle 700 °C Image courtesy Oak Ridge National Lab





Fullerene 1200 °C Image courtesy CIC nanoGUNE

a)100°C



78%

AuAg Nanoparticles EDS, 400 °C Image courtesy University of Manchester

Ferroelectric Nanoparticles 700 °C *Image courtesy Dr. Matias Acosta*

Au on Ti EBSD Image courtesy JEOL USA \sum_{n}

22%



ZnO/Al₂O₃ Fibers 750 °C Image courtesy Dr. Hessam Ghassemi









Au on Fe₂O₃ 600 °C – 700 °C Image courtesy Oak Ridge National Lab

WATCH

DYNAMIC

CHANGES

ACHIEVE HIGH RESOLUTION





SETTLES FAST with minimal displacement

Fusion combines a new low-power E-chip[™] technology with holders constructed using special alloys to dissipate heat. The result is minimal displacement and drift during heating experiments. With only nanometers of displacement during changes of hundreds of degrees, easily follow your area of interest even at the highest magnifications when heating and quenching your sample.



>99.5%





ACCURACY & UNIFORMITY everywhere you image

rotoch

Temperature accuracy starts with thermal uniformity. A non-uniform heating surface is not at a single temperature, therefore knowing the precise temperature of your sample is nearly impossible. Fusion's proprietary ceramic heating technology integrates the heater and the sample support area into a single thin film with temperature uniformity better than 99.5%.



ELECTRICAL characterization

The fundamental challenge facing electrical experiments in the TEM or SEM is the very low current required to characterize nanoscale samples. These currents are often less than a nanoamp and must be precisely sourced and measured on a low-parasitic sample support to ensure accurate results. Fusion is a fully featured system that provides single digit picoamp measurements with sensitivity into the attoamps. With over 30 different electrical E- chip variations, there is a sample support for every application.



ELECTROTHERMAL characterization

Until now, it has been impossible to observe and measure electrical properties as a function of temperature inside an electron microscope. Electrothermal E- chips feature a silicon carbide heater with tungsten electrodes that enable researchers to perform these experiments even at high temperatures. The electrothermal function combines the full features and specifications of the Fusion heating and electrical modes into a single easy-to-use software interface.



SOFTWARE CONTROL with image synchronization

Control your experiments with powerful, intuitive Clarity[™] software. Program electrical and/or thermal stimuli as waveforms or change parameters as you go. Observe data in real time with a visual user interface that plots your results. Optional ImageSync[™] software synchronizes images and video with the heating and electrical data, so analyzing your results is fast and easy.

ATTACH FIB LAMELLA for thermal & electrical characterization in SEM or TEM





Semiconductor FIB lamella on E-chip

EDS MAP material transformations







Limestone heated to 1000°C then quenched

ELIMINATE CHARGING on insulating materials by applying temperature





100 °C 900 °C

Mesoporous Silica (insulator)

EBSD phase transformation and recrystallization





Thermal grain growth of gold

HEAT & QUENCH up to 70 microns in size





Molten solder - 20 micron diameter

SEM thermal & electrical characterization

The same E-chip supports for the TEM can be used in an SEM with the Fusion SEM holder. Correlative experiments in the SEM enable analysis of morphology and composition using SE and BSE analysis. Together, the SEM and TEM are the perfect combination to analyze samples and correlate data to form a complete picture of material properties. TEM PRODUCTS THAT ARE SAFE AND COMPATIBLE WITH YOUR MICROSCOPE



Carefully evaluated and approved by your instrument manufacturer

EDS analysis is fundamental to in situ materials research. By collaborating closely with the microscope manufacturers, all Fusion holders are optimized to maximize the collection of EDS signals, even at zero alpha tilt.



Pd on TiO₂ EDS, 500 °C: Image courtesy Argonne National Lab



DOUBLE TILT

Smooth alpha and beta tilting and variable-speed finger touch controls enable precise, stable holder positioning. The E-Chip and the electrical contacts tilt together during beta tilt, providing excellent mechanical and electrical stability, while touch detection controls ensure microscope safety.



"The Protochips system was integral to the success of the experiments. Repeatable image stability during heating with minimal sample drift allowed reliable acquisition of electron holograms. The steady heating and cooling rates enabled consistent repeatable experiments, which otherwise would have influenced the thermomagnetic behavior."

- Dr. Trevor Almeida, University of Glasgow



"For the first time I can now simultaneously heat and apply an electric field to my sample within the electron microscope. With this system I can observe the dynamic processes and mechanisms of field assisted sintering as they occur."

- Dr. Klaus Van Bentham, University of California, Davis



Over 140 scientific peerreviewed journal articles

Over 150 heating systems in the market

Over 1300 citations

"Our in situ work required a very stable double-tilt heating system to obtain atomic resolution of on-axis images while applying temperature changes to the sample. Without the Protochips heating system, our results would not have been possible."

- Dr. James LeBeau, North Carolina State University



ONE SYSTEM, ENDLESS POSSIBILITIES

FUSION SPECIFICATIONS

TEM HOLDERS

Microscopes Compatibility Alpha Tilt Beta Tilt (Option)

Most Manufacturers and Models EDS, EELS, STEM, Diffraction, ETEM, Raman, Holography Up to ± 55° (varies by model) ± 10°

Microscopes Compatibility Loading

Most Manufacturers and Models SE, BSE, EDS, EBSD, STEM, Raman Load Lock & Direct Mounting

SEM HOLDERS



HEATING

Max Temperature* Temperature Uniformity Temperature Accuracy Temp Stability Heating & Cooling Rate Low Displacement Sample Supports Max Resolution Ultimate Drift Rate Interchangeable E-Chips 1200 °C (900 °C for Electrothermal)
99.5%
95%
0.01 °C
Any rate up to 1000 °C/ms
7 nm at 5 seconds with 325 °C ΔT
Through Hole - Silicon Nitride - Holey Carbon
0.6 Å
0.5 nm/minute
Interchangeable E-chips | Between all TEM and SEM holders



Max Current Max Voltage Max Electric Field AC E-Chip Configurations E-Chips Current Measurement Accuracy Voltage Measurement Accuracy

ELECTRICAL

100 mA 55 V, inquire for higher Up to 100 kV/cm Low Frequency 30 Interchangeable E-chips | Between all TEM and SEM holders $\pm 0.15\% + 750$ fA $\pm 0.015\% + 225 \mu$ V



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